

## **DYNAMIC OVERDRIVE COMPENSATION TEST SYSTEM AND METHOD**

### **ABSTRACT**

The invention(s) relates to a wafer test system including means capable of  
5 communicating an overdrive to a chuck, the chuck moving a wafer towards a probe head  
responsive to the overdrive, measuring a contact resistance of at least one channel in each of a  
plurality of dies associated with the wafer using the probe head, computing a per channel  
standard deviation responsive to measuring the contact resistance, comparing the standard  
deviation on the at least one channel to a threshold, and increasing the overdrive responsive  
10 to the comparison.